

Amendment to the Abstract:

Please replace the previous Abstract on page 56 of the application, with the following new Abstract:

ABSTRACT OF THE INVENTION

~~A MEMS scanning device has a variable resonant frequency. In one embodiment, the MEMS device includes a flexible arm that extends from an oscillatory body. An electrical field applies a force to the flexible arm, thereby bending the flexible arm to change the moment of inertia of the oscillatory body and a secondary mass carried by the flexible arm. The shifted combined center of mass changes the resonant frequency of the MEMS device. In another embodiment, an absorptive material forms a portion of a torsional arm that supports the oscillatory body. The mechanical properties of the absorptive material can be varied by varying the concentration of a gas surrounding the absorptive material. The varied mechanical properties change the resonant frequency of the scanning device. A display apparatus includes the scanning device and the scanning device scans about two or more axes, typically in a raster pattern. Various approaches to controlling the frequency responses of the scanning device are described, including active control of MEMS scanners and passive frequency tuning.~~

Replace the deleted text with the following new text:

A micro-electromechanical system (MEMS) scanner may be used in a range of systems including a scanned beam display or a scanned beam image capture system. The MEMS scanner may include provision for movement or oscillation in two or more axes. A mass asymmetry is introduced to the scanner. The mass asymmetry induces an oscillation component in an axis orthogonal to a primary axis of movement. The asymmetric mass may be formed by a number of means including selective application and selective removal. In some applications, the mass may be selectively formed or removed in an array of locations. The frequency, phase, and direction of induced oscillation component may be selected.